

AUG 01 2007

<b>Form 1449 (Modified)</b>  <b>Information Disclosure Statement By Applicant</b>  (Use Several Sheets if Necessary)	Atty Docket No. NOVLP068/NVLS-2818	Application No.: 10/690,084
	Applicant: Koos et al. Filing Date October 20, 2003	Group 1765

**U.S. Patent and Publication Documents**

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub- class	Filing Date
	A1						

**Foreign Patent or Published Foreign Patent Application**

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub- class	Translation	
							Yes	No
	B1							

**Other Documents**

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
/LV/	C1	Office Action mailed July 27, 2007, from U.S. Application No. 11/586,394 [NOVLP068X1/NVLS-2818C1]
Examiner	/Lan Vinh/	Date Considered 09/28/2007

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

AUG. 28. 2007 12:33PM

5106630920

RECEIVED  
CENTRAL FAX CENTER

NO. 025

P. 16

AUG 28 2007

Form 1449 (Modified)	Atty Docket No. NOVLP068/NVLS-2818	Application No.: 10/690,084
Information Disclosure Statement By Applicant	Applicant: Koos et al.	
(Use Several Sheets if Necessary)	Filing Date October 20, 2003	Group 1765

## U.S. Patent and Publication Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub- class	Filing Date
/LV/	A1	7,049,234	05/2006	Cheng et al.			
↓	A2	2005/026625	12/2005	Cheng et al.			
↓	A3	2003/0190426	10/2003	Padhi et al.			
↓	A4	2003/0059526	10/2003	Chung et al.			
/LV/	A5	2004/0253740	12/2004	Shalyt et al.			


## Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub- class	Translation	
	B1						Yes	No

## Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	C1	
Examiner /LV/		Date Considered 09/28/2007

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



<b>Form 1449 (Modified)</b>  <b>Information Disclosure Statement By Applicant</b>  (Use Several Sheets if Necessary)	<b>Atty Docket No.</b>	NOVLP068/NVLS-2818
	<b>Application No.:</b>	10/690,084
	<b>Applicant</b>	Koos et al.
	<b>Filing Date</b>	October 20, 2003
	<b>Group</b>	1765
		Page 1 of 1

**U.S. Patent Documents**

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
	1.						
	2.						
	3.						

**Foreign Patent or Published Foreign Patent Application**

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-Class	Translation	
							Yes	No
	4.							

**Other Documents**

Examiner Initial	No.	Author, Title, Place (e.g. Journal) of Publication, Date
/LV/	5.	U.S. Final Office Action mailed July 18, 2007 from U.S. Application No. 11/251,353. [NOVLP141/NVLS-3107]
/LV/	6.	SanderKok.com, "Analytical Chemistry", <a href="http://home.planet.nl/-skok/ttechniques/laboratory/pka_pkb.htm">http://home.planet.nl/-skok/ttechniques/laboratory/pka_pkb.htm</a> .

<b>Examiner</b> /Lan Vinh/	<b>Date Considered</b> 09/28/2007
----------------------------	-----------------------------------

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<b>Form 1449 (Modified)</b> <b>Information Disclosure</b> <b>Statement By Applicant</b>  (Use Several Sheets if Necessary)	<b>Atty Docket No.</b>	NOVLP068/NVLS-2818
	<b>Application No.:</b>	10/690,084
	<b>Applicant</b>	Koos et al.
	<b>Filing Date</b>	October 20, 2003
	<b>Group</b>	1765
		Page 1 of 1

#### U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
/LV/	1.	7,056,648	06.2006	Cooper et al.			
/LV/	2.	4,181,760	01.1980	Feldstein, Nathan			
/LV/	3.	2002/0084529	07.2002	Dubin et al.			

#### Foreign Patent or Published Foreign Patent Application

Examiner Initial		Document No.	Publication Date	Country or Patent Office	Class	Sub-Class	Translation	
							Yes	No
	4.	JP02111883	04.1990	JPO				

#### Other Documents

Examiner Initial	No.	Author, Title, Place (e.g. Journal) of Publication, Date
/LV/	5.	Mayer et al., "Pad-Assisted Electropolishing," Novellus Systems, Inc., Appln No.: 11/213,190, filed August 26, 2005. [NVLS-3037]
/LV/	6.	Mayer et al., "Topography Reduction and Control by Selective Accelerator Removal," Novellus Systems, Inc., Appln. No.: 11/602,128, filed November 20, 2006. [NVLS-2960]
/LV/	7.	Aksu et al., "The Role of Glycine in the Chemical Mechanical Planarization of Copper," Journal of The Electrochemical Society, 149 (6) G352-G361 (200), Department of Materials Science and Engineering, University of California, Berkeley, Berkeley, California 94720-1760, USA <span style="float: right;">NO DATES</span>
/LV/	8.	U.S. Office Action mailed August 16, 2006 from U.S. Application No. 10/742,006. [NOVLP065/NVLS-2796]

<b>Examiner</b>	/Lan Vinh/	<b>Date Considered</b>	07/30/2007
-----------------	------------	------------------------	------------

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



Form 1449 (Modified)	Atty Docket No. NOVLP068/NVLS-2818	Application No.: 10/690,084
Information Disclosure Statement By Applicant	Applicant: Koos et al.	
(Use Several Sheets if Necessary)	Filing Date October 20, 2003	Group 1765

**U.S. Patent and Publication Documents**

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
LV	A1	4,002,778	1/11/77	Bellis et al.			
	A2	6,692,873	11/8/05	Park			
	A3	5,824,599	10/20/98	Schacham-Diamond, et al.			
	A4	5,695,810	12/9/97	Dubin et al.			
	A5	5,380,560	1/10/94	Kaja et al.			
	A6	6,197,364	3/6/01	Paunovic et al.			
	A7	2002/0084529	07/2002	Dubin et al.			
LV	A8	2003/0176049	09/2003	Hegde et al.			

4B 4-15

**Foreign Patent or Published Foreign Patent Application**

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
LV	B1	JP03122266	05/1991	JPO				

**Other Documents**

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
LV	C1	Sullivan et al, "Electrolessly Deposited Diffusion Barriers For Microelectronics, E. J. IBM J Res Develop Vol 42, No. 4 Sept 1998, 607-620
LV	C2	Eugene J. O'Sullivan, "Electroless Deposition in Microelectronics: New Trend," Electrochemical Society Proceeding Volume 99-34, 159-171 NO PATES LV
LV	C3	T. Itabashi et al., "Electroless Deposited CoWB for Copper Diffusion Barrier Metals," Hitachi Research Laboratory, IEEE, 2002, 285-287 NO PA
LV	C4	N. Petrov and Y. Shacham-Diamand, "Electrochemical Study of the Electroless Deposition of Co(W,P) Barrier Layers for Cu Metallization," Electrochemical Soc. Proceedings Vol. 2000-27, 134-148 NO PATES LV
Examiner /Lan Vinh/		Date Considered 11/22/2006

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.